



Sheet 1 of 1

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## INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

APPLICANT(S)  
Takeshi SHIRAI et al.

FILING DATE  
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GROUP  
2872

## U.S. PATENT DOCUMENTS

Examiner Initials	Cite No.	Document Number	Date	Name
/AA/	1	6,417,974	07/09/2002	Schuster
/AA/	2	2001/0043320 A1	11/22/2001	Kato et al.

## FOREIGN PATENT DOCUMENTS

Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation
/AA/	3	EP 1 152 263 A1	11/07/2001	EPO		
/AA/	4	EP 1 571 700 A1	09/07/2005	EPO		
/AA/	5	EP 1 646 074 A1	04/12/2006	EPO		

## OTHER DOCUMENTS

Examiner Initials	Cite No.	Including name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
/AA/	6	M. SWITKES et al., Immersion Liquids for Lithography in the Deep Ultraviolet, Optical Microlithography XVI, 2003, 690-699, Vol. 5040 (2003)

EXAMINER

/Alessandro Amari/

DATE CONSIDERED  
01/15/2009

Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Date: November 7, 2008